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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/806,885	03/22/2004	Takashi Izuta	P/1596-76	3872
	7590 09/07/200 FABER GERB & SOF	EXAMINER		
	OF THE AMERICAS	MOORE, KARLA A		
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			1763	
			MAIL DATE	DELIVERY MODE
			09/07/2007	PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

		Application No.	Applicant(s)		
Office Action Summary		10/806,885	IZUTA, TAKASHI	IZUTA, TAKASHI	
		Examiner	Art Unit		
		Karla Moore	1763		
	nis communication app	ears on the cover sheet with	the correspondence a	ddress	
Period for Reply  A SHORTENED STATUTORY WHICHEVER IS LONGER, FR - Extensions of time may be available undoughed after SIX (6) MONTHS from the mailing of the control of the	COM THE MAILING DA er the provisions of 37 CFR 1.13 ate of this communication. the maximum statutory period w period for reply will, by statute, in three months after the mailing	ATE OF THIS COMMUNICA: 16(a). In no event, however, may a reply ill apply and will expire SIX (6) MONTHS cause the application to become ABANI	TION. be timely filed from the mailing date of this of DONED (35 U.S.C. § 133).	·	
Status					
<ul> <li>1) ☐ Responsive to communic</li> <li>2a) ☒ This action is FINAL.</li> <li>3) ☐ Since this application is in closed in accordance with</li> </ul>	2b)∭ This n condition for allowar	action is non-final.		e merits is	
Disposition of Claims					
4)  Claim(s) 5-16 is/are pend 4a) Of the above claim(s) 5)  Claim(s) is/are all 6)  Claim(s) 5-16 is/are reject 7)  Claim(s) is/are ob 8)  Claim(s) are subject Application Papers	is/are withdrave owed. cted. jected to.	vn from consideration.			
	tad to butba Fuersia				
	2 March 2004 is/are: a hat any objection to the t(s) including the correct	a) accepted or b) object drawing(s) be held in abeyance on is required if the drawing(s)	See 37 CFR 1.85(a). is objected to. See 37 C	FR 1.121(d).	
Priority under 35 U.S.C. § 119		•			
12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).  a) All b) Some * c) None of:  1. Certified copies of the priority documents have been received.  2. Certified copies of the priority documents have been received in Application No  3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).  * See the attached detailed Office action for a list of the certified copies not received.					
Attachment(s)					
1) Notice of References Cited (PTO-89 2) Notice of Draftsperson's Patent Drav 3) Information Disclosure Statement(s) Paper No(s)/Mail Date	ving Review (PTO-948)	Paper No(s)/M	mary (PTO-413) lail Date mal Patent Application		

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#### DETAILED ACTION

## Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claims 5-9 and 12-14 are rejected under 35 U.S.C. 103(a) as being unpatentable over JP Patent No. 08-067413 to Mitsuyoshi et al. in view of U.S. Patent No. 5,672,230 to Park et al. and Japanese Patent No. 10-247679A to Okuno et al.
- 3. Mitsuyoshi et al. disclose a substrate treating apparatus for performing a predetermined treatment of a plurality of substrates as immersed in a heated treated solution substantially as claimed and comprising: a substrate count acquiring device (9) for acquiring a count of said substrates to be treated and a treating tank device (4) for immersing said substrates in the heated treated solution for the processing.
- 4. However, Mitsuyoshi et al. fail to teach a controller comprising: storage device for storing beforehand a relationship between count of the substrates and processing time for immersion in the heated treating solution; or a processing time determining device for determining a processing time according to said substrate count of said substrates acquired by said substrate count acquiring device, by referencing to said relationship stored in said storage device; as well as the substrate count acquiring device.

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5. Park et al. teach monitoring sensed processing variables during a treatment process and using a main computer/controller (i.e. to coordinate a substrate acquiring device, a storage device and processing time determining means) to display, store and

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process sensed data to thereby enable effective central management of the treatment

process (abstract).

6. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided a main computer acting as a storage device and processing time determining means in Mitsuyoshi et al. in order to display, store and process sensed data thereby enabling effective central management of a treatment process as taught by Park et al.

- 7. Examiner notes that the claimed invention teaches that the storage device and the process time determining means are part of a single controller/computer.
- 8. Mitsuyoshi et al. and Park et al. fail explicitly teach the storage device capable of storing predetermined ranges of substrate counts, such that a processing time for an entire predetermine range of counts of said substrates corresponds to a predetermined immersion time for one of said counts in said predetermined range.
- 9. Okuno et al. teach providing a controller comprising a storage device having the capability of storing predetermined ranges of substrate counts, such that a processing time for an entire predetermine range of counts of said substrates corresponds to a predetermined processing time for one of said counts in said predetermined range (abstract). Further, it would have been clear to one of ordinary skill in the art that as the

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number of substrates increased, the processing time would need to progressively increase and if the number of substrates decreased the processing time would decrease.

- 10. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention was made to have provided a controller comprising a storage device having the capability of storing predetermined ranges of substrate counts, such that a processing time for an entire predetermine range of counts of said substrates corresponds to a predetermined processing/immersion time for one of said counts in said predetermined range in Mitsuyoshi et al. and Park et al. in order to execute a processing treatment without deteriorating the qualities of substrates when the number of substrates processed in a single treatment may vary as taught by Okuno et al.
- 11. With respect to claims 6, the optical sensor of Mitsuyoshi et al. is a transmission type sensor.
- 12. With respect to claims 7 and 8, although Mitsuyoshi et al. do not explicitly teach using different types of sensors, one of ordinary skill in the art would recognize that any sensor capable of sensing the presence of wafers could be used for counting the wafers. The courts have ruled that an express suggestion to substitute one equivalent component or process for another is not necessary to render such substitution obvious. In re Fout, 675 F.2d 297, 213 USPQ 532 (CCPA 1982).
- 13. With respect to claim 9, Mitsuyoshi et al. further comprises a container rest (Figure 1, 2) for receiving a container (Figure 1, C) storing said substrates to be treated,

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said substrate count acquiring device counts said substrates in said container placed on said rest.

- 14. With respect to claim 12, Mitsuyoshi et al. disclose a substrate loading robot (10). Further, with respect to the recitation of the claim drawn to the placement of the counting device, the courts have ruled that the mere rearrangement of parts which does not modify the operation of a device is prima facie obvious. <u>In re Japikse</u>, 181 F.2d 1019, 86 USPQ 70 (CCPA 1950). <u>In re Kuhle</u>, 526 F.2d 553, 188 USPQ 7 (CCPA 1975).
- 15. With respect to claim 13, Park et al. teaches that data may be acquired from an external device (column 4, rows 15-18).
- 16. With respect to claim 14, the substrate count acquiring device in Park et al. is a computer which would be capable of acquiring key input from a control unit.
- 17. Claims 10-11 and 15-16 are rejected under 35 U.S.C. 103(a) as being unpatentable over Mitsuyoshi et al., Park et al. and Okuno et al. as applied to claims 5-9 and 12-14 above, and further in view of U.S. Patent No. 5,431,179 to Miyazaki et al.
- 18. Mitsuyoshi et al., Park et al. and Okuno et al. disclose the invention substantially as claimed and as described above.
- 19. However, Mitsuyoshi et al., Park et al. and Okuno et al. fail to teach shutters for opening and closing partition acting as an atmospheric barrier between said container rest and a treating tank.

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20. Miyazaki et al. teach using shutters for preventing vapor from leaking outside a

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process apparatus (column 5, rows 28-40).

21. It would have been obvious to one of ordinary skill in the art at the time the Applicant's invention to have provided shutters for opening and closing a partition acting as a barrier in said treating tank device in Mitsuyoshi et al., Park et al. and Okuno et al. in order to prevent vapor from leaking outside the process apparatus as taught by

Miyazaki et al.

22. Further, with respect to these claims, which recite placing the counting device at various places in the apparatus, the courts have ruled that the mere rearrangement of parts which does not modify the operation of a device is prima facie obvious. <u>In re Japikse</u>, 181 F.2d 1019, 86 USPQ 70 (CCPA 1950). <u>In re Kuhle</u>, 526 F.2d 553, 188 USPQ 7 (CCPA 1975).

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23. With respect to claims 15-16, Miyazaki et al. provide a plurality of treatment sections sequentially arranged, for performing a series of treatment steps (column 3, rows 35-62). When one process is over the substrates can be transferred to the next. Further, the processing fluid in each of the sections can be drained and replaced as needed (column 3, rows 62-66).

## Response to Arguments

24. Applicant's arguments with respect to claims 5-16 have been considered but are moot in view of the new ground(s) of rejection. See above.

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### Conclusion

25. Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Karla Moore whose telephone number is 571.272.1440. The examiner can normally be reached on Monday-Friday, 9:00 am-6:00 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on 571.272.1435. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Kara Moore

Primary Examiner

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4 September 2007